

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicants:	Den Toonder, <i>et al.</i>	Docket No.:	EPC-018
Serial No.:	10/578,027	Art Unit:	1733
Filed:	November 6, 2008	Examiner:	Janell C. Morillo
For:	Radio-Frequency Microelectromechanical Systems and a Method of Manufacturing Such Systems		

Commissioner for Patents  
P. O. Box 1450  
Alexandria, VA 22313-1450

**INFORMATION DISCLOSURE STATEMENT**

Dear Sir:

The Applicants wish to bring to the attention of the Patent and Trademark Office the information noted on the enclosed form PTO/SB/08a that may be considered material to the examination of the above-identified application. Applicants have included a copy of the cited foreign patent. By this submission, Applicants are not asserting or acknowledging that the cited reference is prior art under 35 U.S.C. § 102.

No fee is due at this time, as this Information Disclosure Statement is being filed pursuant to 37 C.F.R. § 1.97(c)(1). Applicants hereby state that each item of information contained in this statement was first cited in a communication from a foreign patent office in a counterpart application not more than three months prior to the filing of this statement. A copy of the Japanese Examination Report is provided for the Examiner's convenience.

Respectfully submitted,

December 23, 2011

Date

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